

Atty. Dkt.: APPM/005975.P1/CPI/COPPER/LB/PJS

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Chang, et al.

Serial No.: 10/634,662

Filed:

August 4, 2003

Confirmation No.: 6355

For:

Ruthenium Layer

Formation for Copper Film

Deposition

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Group Art Unit: 1762

Examiner:

Markham, Wesley P.

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE OF MAILING 37 CFR 1.8

I hereby certify that this correspondence is being deposited on January 13, 2006 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

January 13, 2006

Date

## PRELIMINARY AMENDMENT

Prior to examination, please amend the above-identified application as follows. Although the Applicant believes that no additional fees are due in connection with this Preliminary Amendment, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/005975.P1/KMT, for any fees, including extension of time fees or excess claim fees, required to make this Preliminary Amendment acceptable to the Office.

Amendments to the Specification begin on page 2 of this paper. Amendments to the Claims begin on page 9 of this paper. Amendments to the Drawings begin on page 19 of this paper and include two attached Replacement Sheets and two attached annotated sheets showing changes. Remarks begin on page 20 of this paper.